

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Kenji NISHI

Appln. No.:

Filed: Herewith

For: PROJECTION EXPOSURE APPARATUS

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

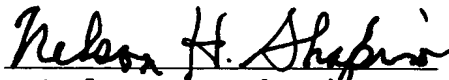
Applicant wishes to make of record the documents cited in predecessor Application Nos. 10/199,324 filed July 22, 2002, 09/572,560 filed May 16, 2000, 09/195,989 filed November 20, 1998, 08/906,429 filed August 5, 1997, 08/547,147 filed October 24, 1995, 08/254,672 filed June 6, 1994, 08/068,101 filed May 28, 1993, whether cited by applicant or by the Patent Office.

Documents from the predecessor applications are listed on the attached Form PTO-1449. Document AL on the attached List is a counterpart of Document AF* and Document AM on the attached List is a counterpart of Document AA.

Respectfully submitted,

NHS:lmb

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November 26, 2003

By: 
Nelson H. Shapiro
Reg. No. 17,095

FORM PTO-1449				Atty. Docket No. XA-7709G		Appln. No.	
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>							
				Applicant Kenji NISHI			
				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	5,194,893	03/1993	Nishi	355	53	
	AB	5,281,996	01/1994	Bruning et al.	355	77	
	AC	5,227,839	07/1993	Allen	355	53	
	AD	3,819,265	06/1974	Feldman et al.	355	51	
	AE	4,953,960	09/1990	Williamson	350	442	
	AF	5,089,913	02/1992	Singh et al.	359	727	
	AG	5,238,870	08/1993	Tanaka	437	173	
	AH	5,285,236	02/1994	Jain	355	53	
	AI	5,291,240	03/1994	Jain	355	53	
	AJ	5,912,727	06/1999	Kawai	355	67	
	AK	4,734,746	03/1988	Ushida et al.	355	53	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AL	2-229423	09/1990	JAPAN (Laid-Open)			No
	AM	4-277612	02/1992	JAPAN			No
	AN	1-91419	04/1989	JAPAN			Yes
OTHER (including author, title, date, pertinent pages, etc.)							
	AO	Tracy et al., "Exposure Dose Control Techniques for Excimer Laser Lithography" in SPIE Vol. 922 <u>Optical/Laser Microlithography</u> , 1988, pp. 437-443.					
	AP	Rominger, "Seamless Stitching for Large Area Integrated Circuit Manufacturing" in SPIE Vol. 922 <u>Optical/Laser Microlithography</u> , 1988, pp. 188-193.					
	AQ	Buckley et al., "Step and scan: A system overview of a new lithography tool" in SPIE Vol. 1088 <u>Optical/Laser Microlithography II</u> , 1989.					
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							

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				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	BA	4,191,466	03/1980	Gandini	355	53	
	BB	4,030,825	06/1977	Ghougasian	355	71	
	BC	5,656,402	08/1995	Kasuga	430	22	
	BD	4,918,320	03/1988	Hamasaki et al.	250	548	
	BE	5,677,754	06/1995	Makinouchi	355	53	
	BF	4,924,257	05/1990	Jain	355	53	
	BG	4,747,678	05/1988	Shafer et al.	350	505	
	BH	5,105,075	04/1992	Ohta et al.	355	53	
	BI	5,473,410	12/1995	Nishi	355	53	
	BJ	5,214,489	05/1993	Mizutani et al.	356	363	
	BK						
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	BL	63-128713	06/01/88	Japan			Yes
	BM						
	BN						
OTHER (including author, title, date, pertinent pages, etc.)							
	BO						
	BP						
	BQ						
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				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	CA	5,661,546	09/1994	Taniguchi	355	53	
	CB	5,365,342	11/1994	Ayata et al.	356	401	
	CC	6,018,395	01/2000	Mori et al.	356	401	
	CD	5,835,196	11/1998	Jackson	355	53	
	CE	5,854,671	12/1998	Nishi	355	53	
	CF	6,072,184	06/2000	Okino et al.	250	492.2	
	CG	6,118,517	09/2000	Sasaki et al.	355	53	
	CH	5,289,231	02/1994	Magome et al.	355	53	
	CI	4,699,515	10/1987	Tanimoto	356	40	
	CJ	5,801,832	9/1998	Van Den Brink	365	500	
	CK	6,249,335	6/2001	Hirukawa et al.	355	53	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	CL						
	CM						
	CN						
OTHER (including author, title, date, pertinent pages, etc.)							
	CO						
	CP						
	CQ						
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U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub- class	Filing Date
	DA	3,538,828	11/10/70	Genovese	95	18	
	DB	4,659,225	4/21/87	Takahashi	356	358	
	DC	4,748,478	5/31/88	Suwa et al.	355	53	
	DD	4,749,867	6/7/88	Matsushita et al.	250	442.1	
	DE	4,822,975	4/18/89	Torigoe	219	121.85	
	DF	5,004,348	4/2/91	Magome	356	401	
	DG	5,187,519	2/16/93	Takabayashi et al.	355	53	
	DH	5,506,684	4/9/96	Ota et al.	356	401	
	DI	5,767,948	6/16/98	Loopstra et al.	355	53	
	DJ	5,796,469	8/18/98	Ebinuma	355	53	
	DK						
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub- class	Translation
	DL	4-235558	8/24/92	JAPAN (Laid-Open)			Yes
	DM						
	DN						
OTHER (including author, title, date, pertinent pages, etc.)							
	DO						
	DP						
	DQ						
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